

# Introduction to 3D Digital SiPM and Latest Results for Particle Physics

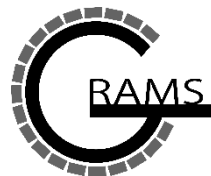
**Jean-François Pratte**

Simon Carrier, Audrey Corbeil Therrien, Keven Deslandes,  
Pascal Gendron, Michel Labrecque-Dias, William Lemaire,  
Frédéric Nolet, Samuel Parent, Charles Richard, Nicolas  
Roy, Tommy Rossignol, Gabriel St-Hilaire, Frédéric Vachon,  
Fabrice Retiere, Henri Dautet, Réjean Fontaine, Serge A.  
Charlebois

2019 CAP Congress – Simon Fraser University (Burnaby, BC)



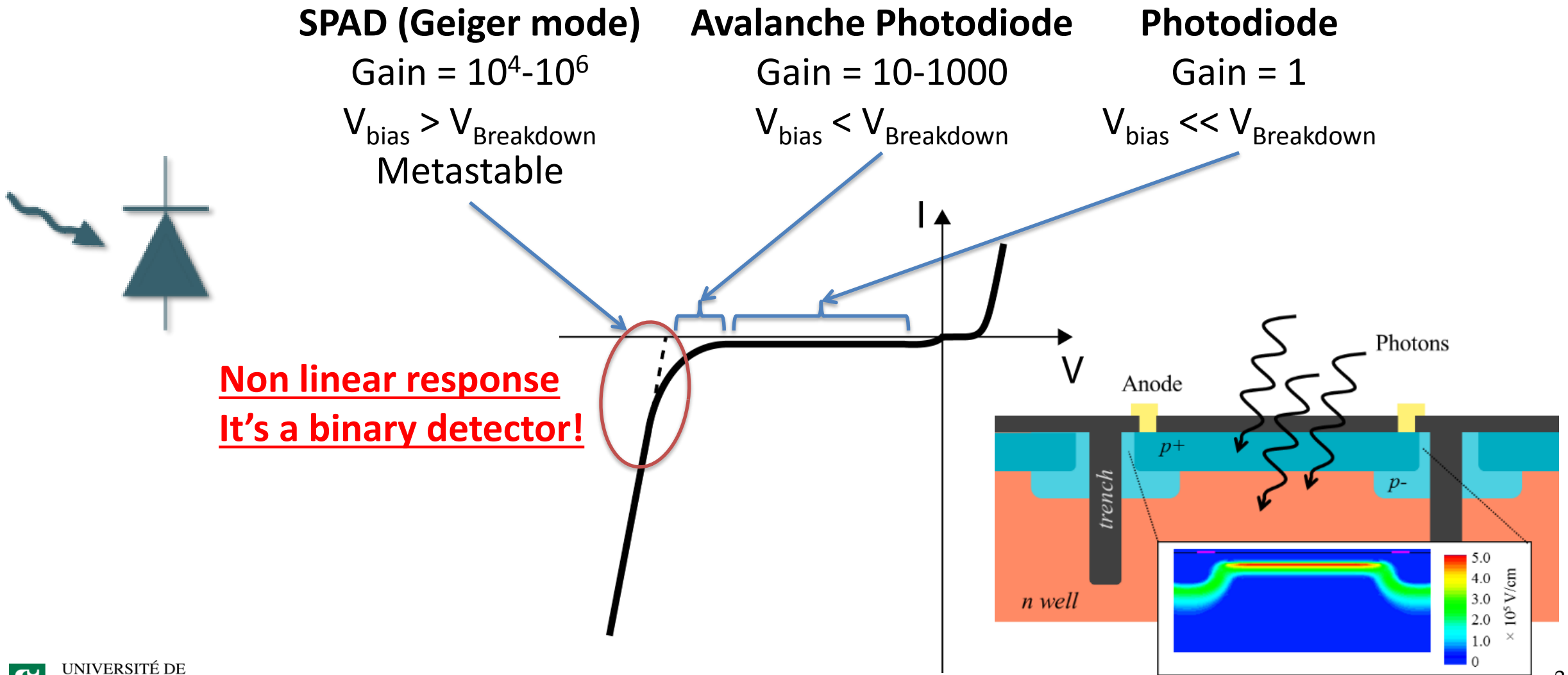
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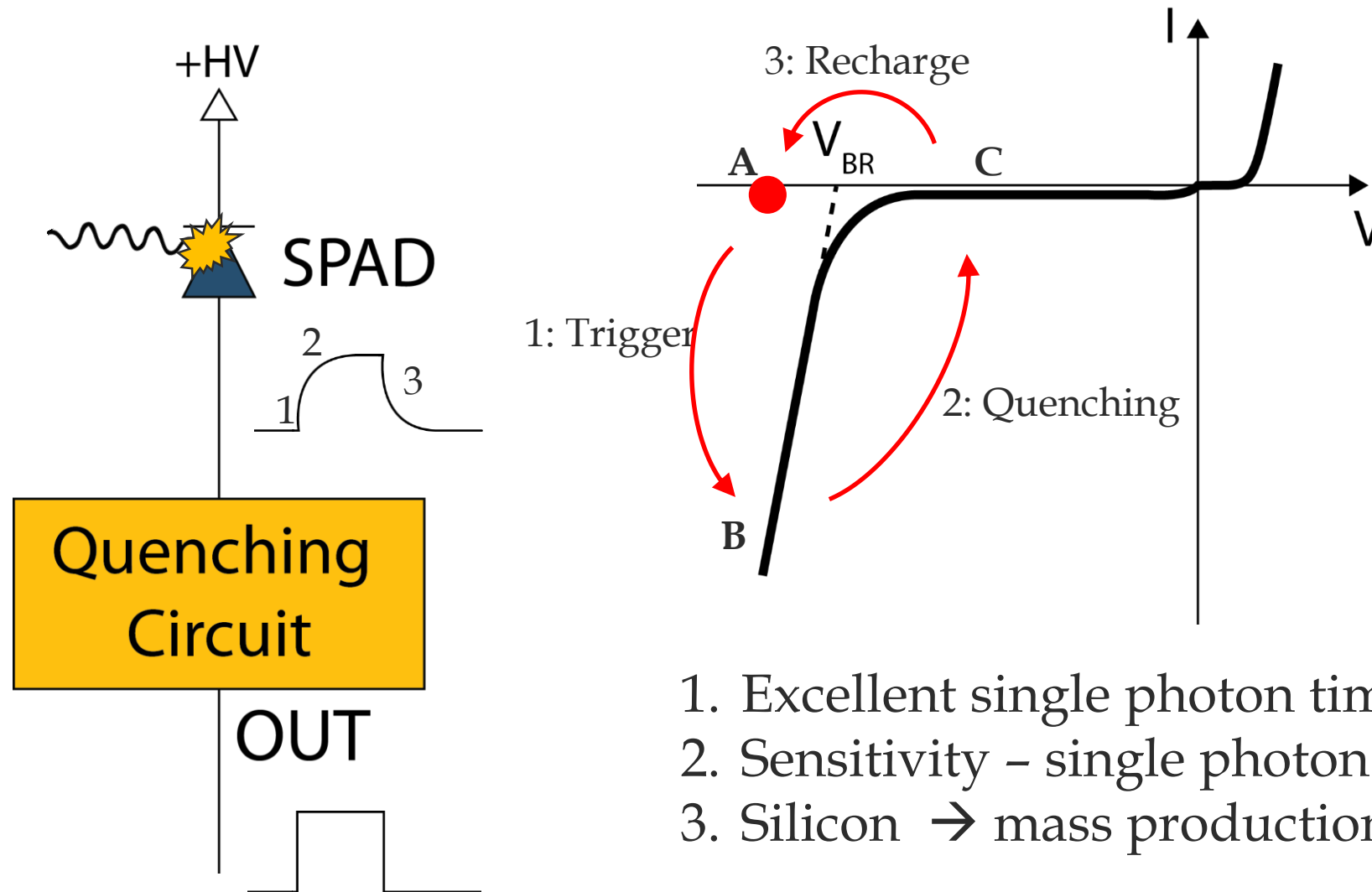
What is a Single Photon Avalanche Diodes (SPAD)?



# Diode I-V Curve and Operating Regime



# Single Photon Avalanche Diode (SPAD) Operation Cycle



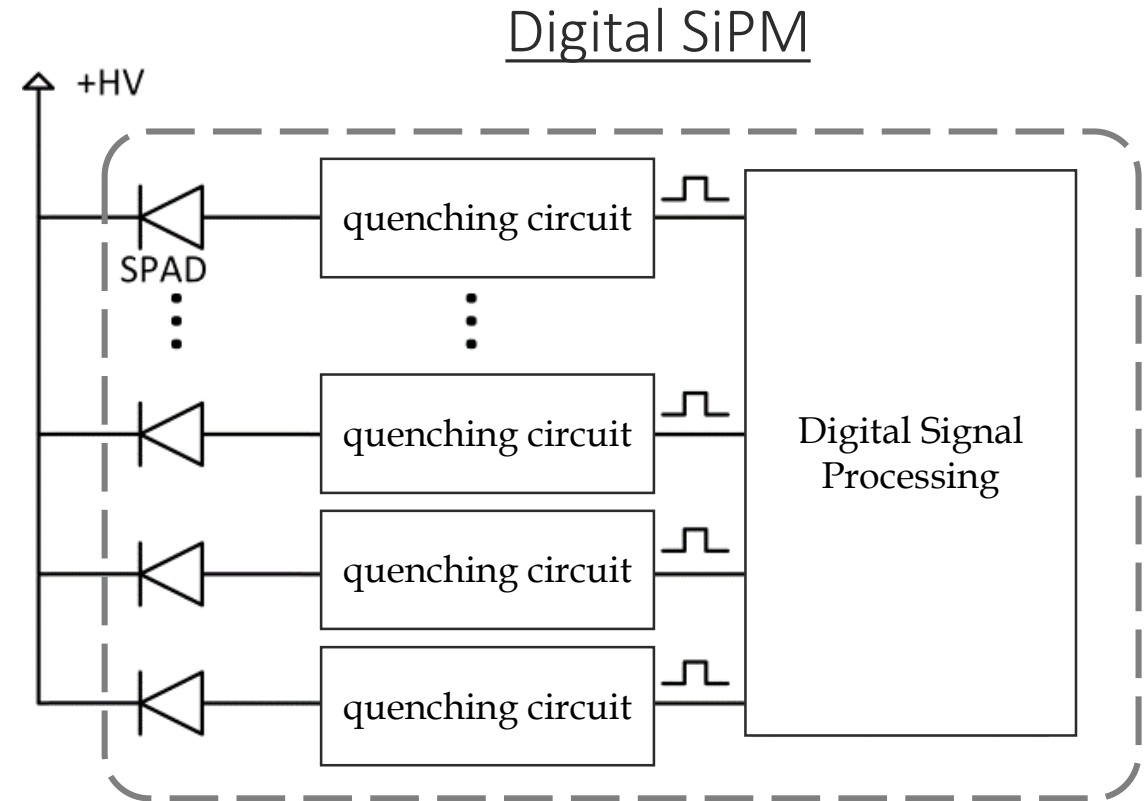
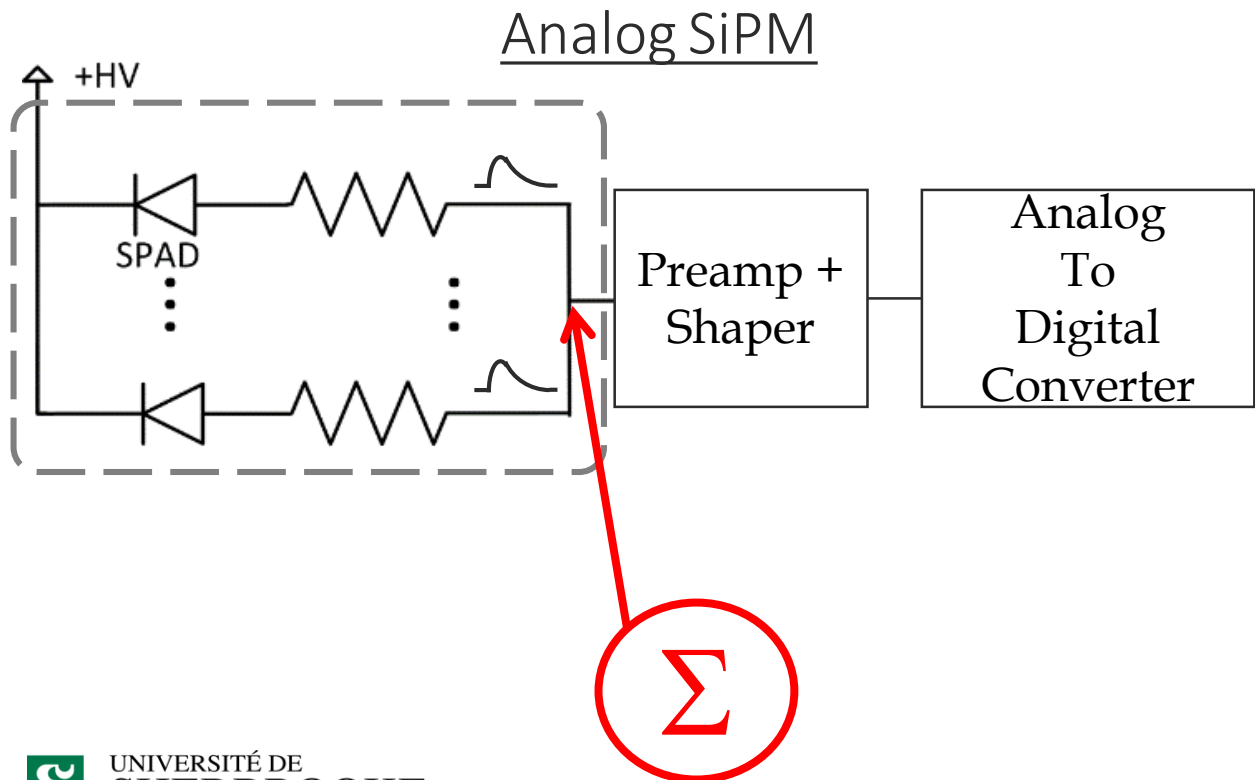
1. Excellent single photon timing resolution
2. Sensitivity - single photon counting
3. Silicon → mass production → low cost

# Analog VS Digital Silicon Photomultiplier (SiPM)



# Analog and Digital Silicon PhotoMultiplier (SiPM): The Definition

Single photon avalanche diode (SPAD) is the basic unit cell of analog and digital SiPM



# Analog and Digital SiPM

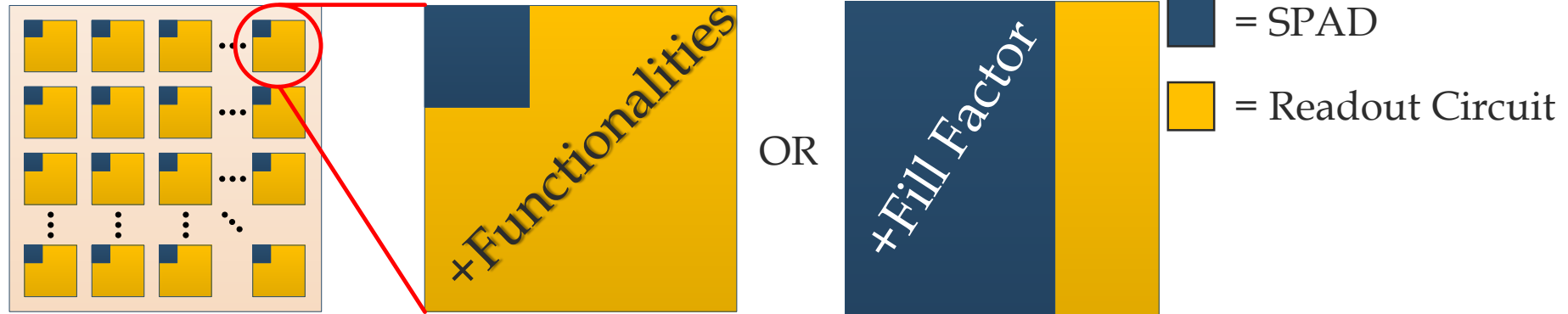
- A SPAD is a **Boolean detector**: **digital information available at the sensor level**
- With an **analog SiPM** we sum binary detectors (an array of SPAD) to get a linear response...
  - Then, use a current/transimpedance amplifier + shaper + ADC

**To digitize the data... again!**
- With a **digital SiPM**, each SPAD is coupled **one-to-one** with its individual readout circuit.
  - **Photon to bit conversion** at the sensor level
  - Improved noise immunity
  - Output capacitance is not an issue (compared to SiPM)
  - Single photon counting mitigated
  - Control over each SPAD: faulty or radiation damaged = shut off
  - Lower dead time (sense-quench-recharge < 10 ns)
  - Mitigates afterpulsing noise
  - No trigger = Low power consumption

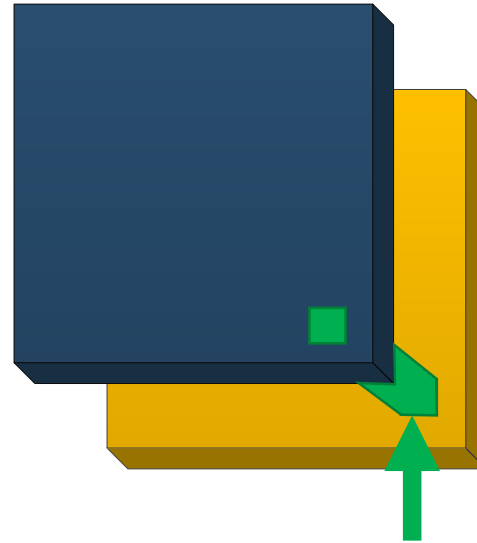
# 3D Digital SiPM VS 2D Digital SiPM



# 2D Digital SiPM: Trade off and Solution → 3D Digital SiPM



IDEALLY:

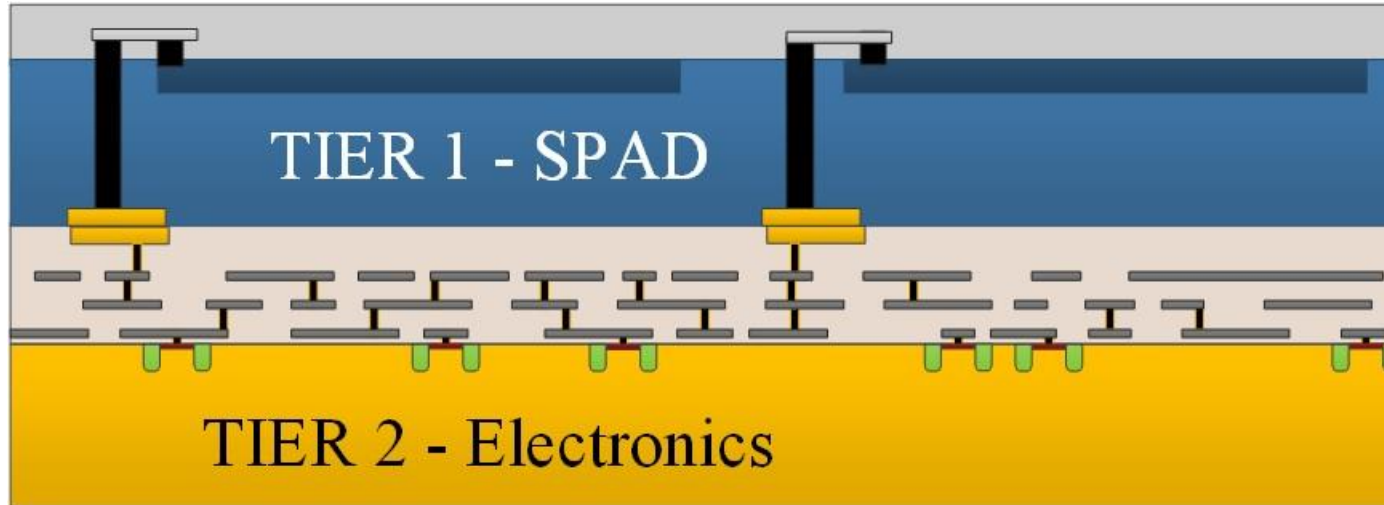


TSV = Through Silicon Via

TSV

- High fill factor for improved photosensitive area
- Freedom for in-pixel electronics functionalities
- Heterogeneous technologies
  - SPAD in optimal technology with
  - CMOS readout circuits in optimal process for application specific functionalities

# 3D Digital SiPM



# 3D Digital SiPM (3DdSiPM) for Low Power and Large Area Detectors



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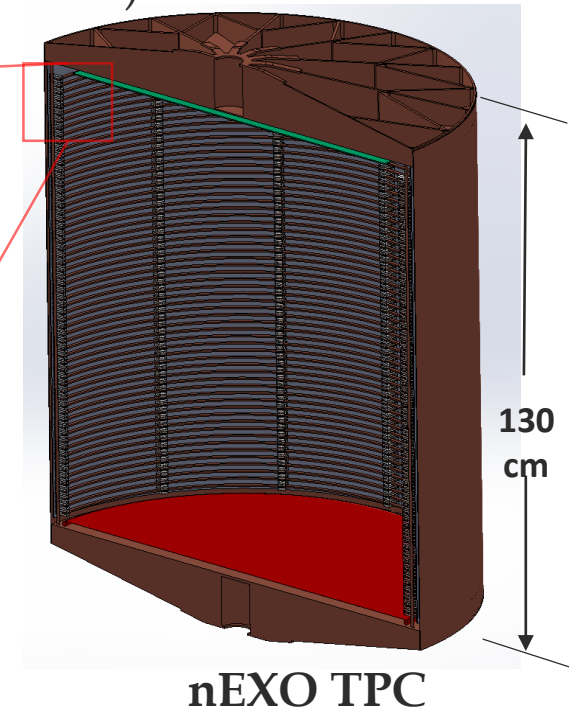
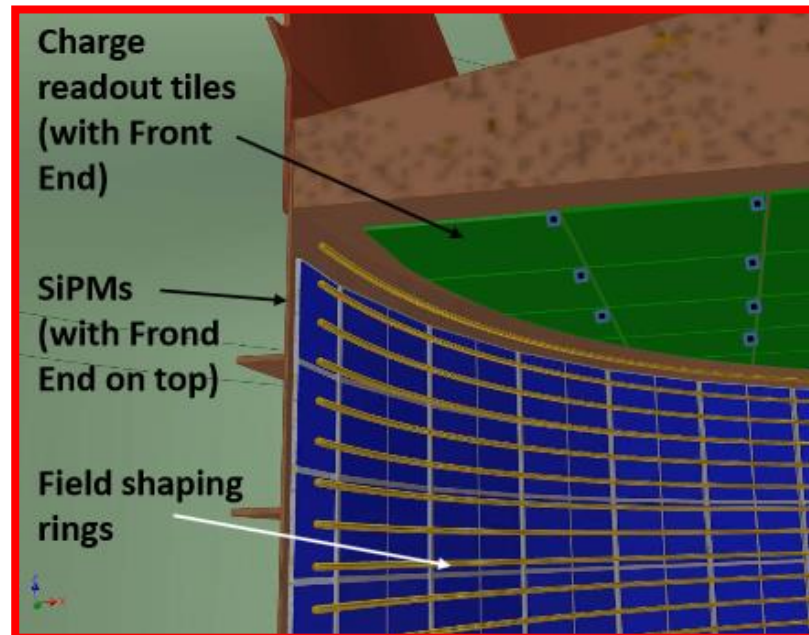
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# nEXO – Search for $0\nu\beta\beta$ - Baseline Design

- 5T liquid Xenon, enriched  $^{136}\text{Xe}$
- Charge TPC and scintillation readout
- Analog SiPM on silicon interposer
  - Photosensitive surface: 4 - 5  $\text{m}^2$
  - $\sim 1 \times 1 \text{ cm}^2$  SiPM in tiles  $\sim 10 \times 10 \text{ cm}^2$
  - Power budget for scintillation readout: 50 W (100 W with data transmission)



# Liquid Argon Detector with Pulse Shape Discrimination

## CFI Innovation Fund 2017

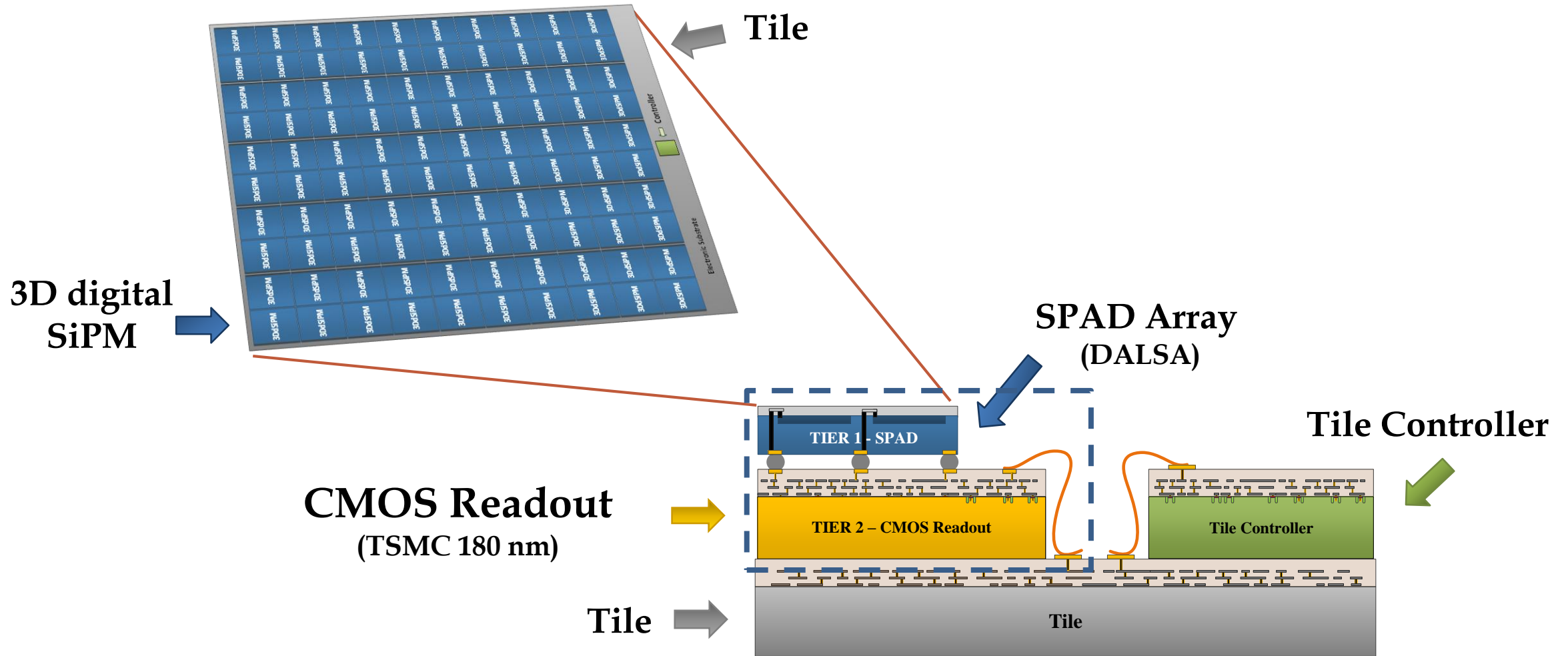
Title: Facility for Development of Cryogenic Detectors and Readout Systems  
for Subatomic Physics and Particle Astrophysics

Principal investigator: Mark Boulay (Carleton)

Université de Sherbrooke contributions: 3D digital SiPM with Embedded Digital  
Signal Processing for Pulse Shape  
Discrimination in LAr

Low Power 3D Digital SiPM for nEXO

# The Goal: Tile of 3DdSiPM with a Controller



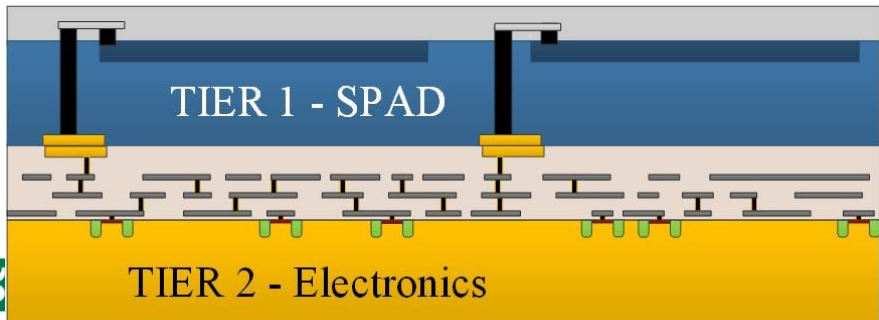
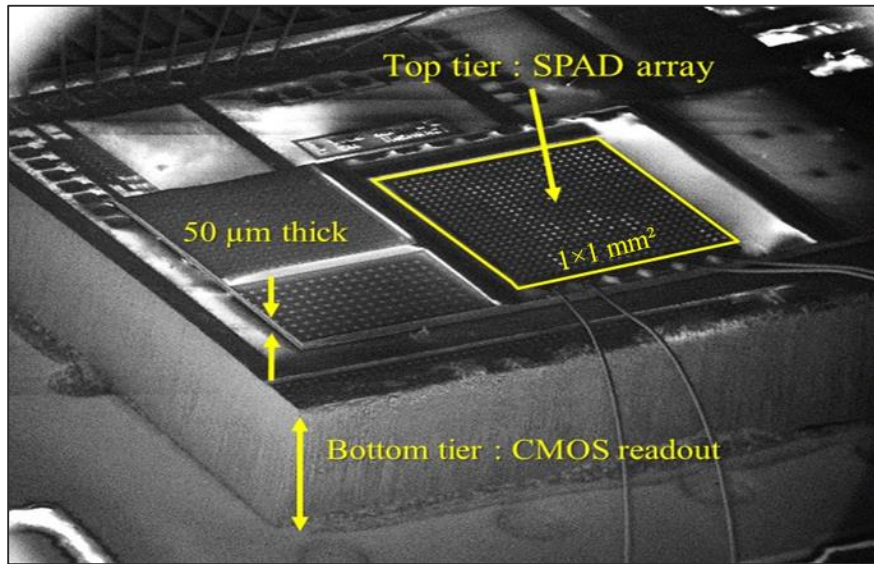
# Development of the 3DdSiPM Technology: The SPAD Array and the 3D Vertical Integration Process



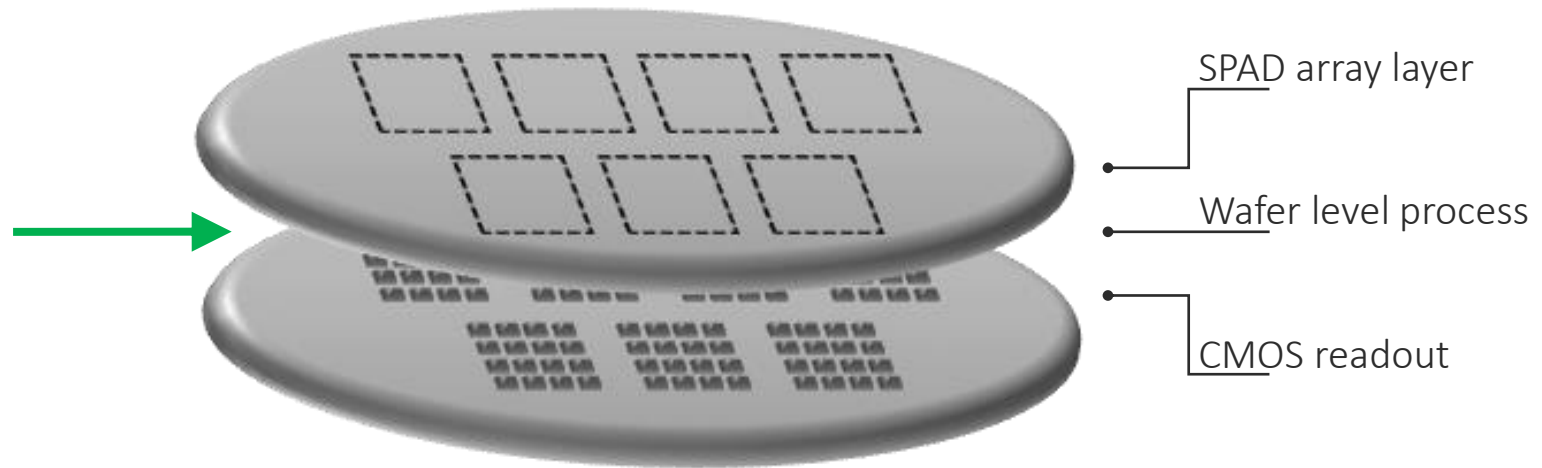


# How to Build a Fully Industrial 3D Digital SiPM ?

2016: First 3D digital SiPM prototype



Wafer scale / industrial process  
3D digital SiPM technology

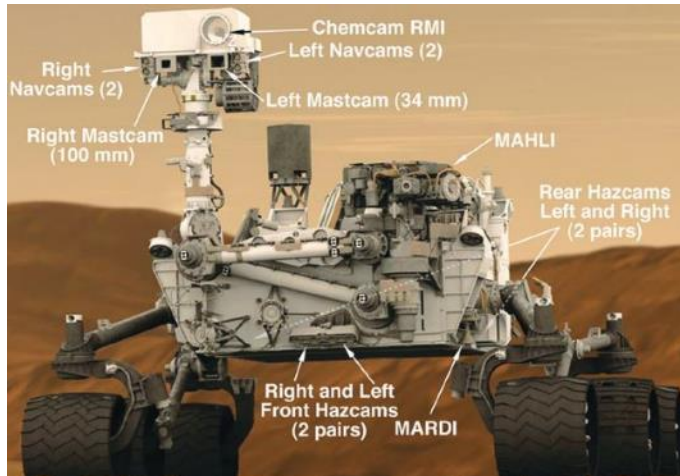


# Main Industrial Collaborator : Teledyne DALSA

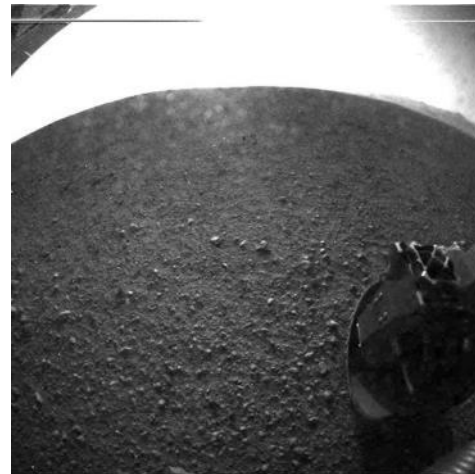
## High-end CCD process line

--> excellent for SPAD R&D

- 150 mm process line
- low contaminant / gold free clean rooms



*The Eyes of the Mars Curiosity Rover.*  
Tech Briefs (2012)



*Life on Mars: Rover landing gives boost to Canadian tech sector.*  
The Globe and Mail (2012)

## World top 5 Microelectromechanical systems (MEMS) Foundry

--> excellent for wafer level integration

- 150 mm and 200 mm process line
- Wafer thinning, deep etching, bonding, ...



*Courtesy of Teledyne DALSA*

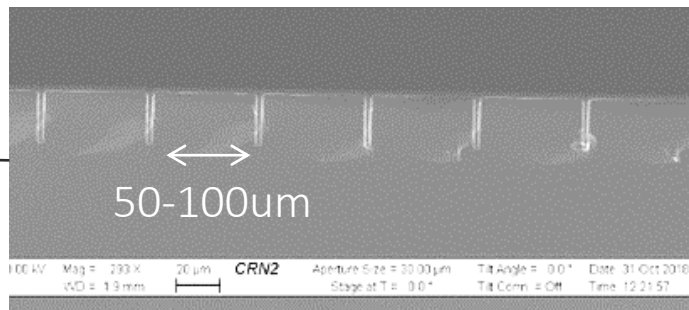
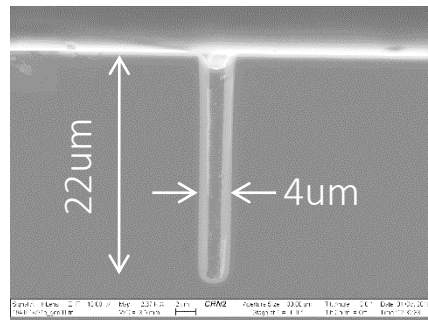
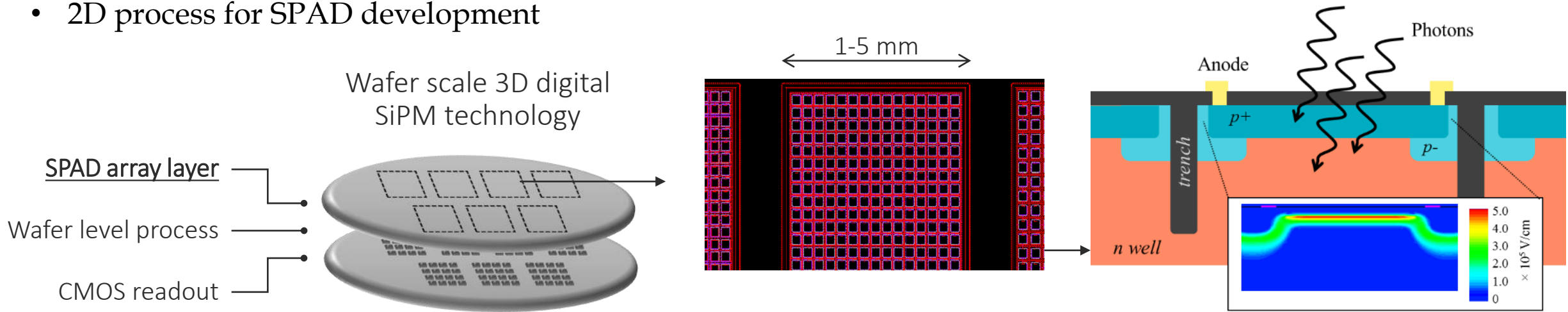
MEMS Foundry Rankings (2017 sales in US\$M)	
STMicroelectronics	174
<b>Teledyne DALSA</b>	60
Silex Microsystems	50
TSMC	47
X-Fab	42

*Status of the MEMS Industry 2018  
Market and technology Report  
Yole Development (2018)*

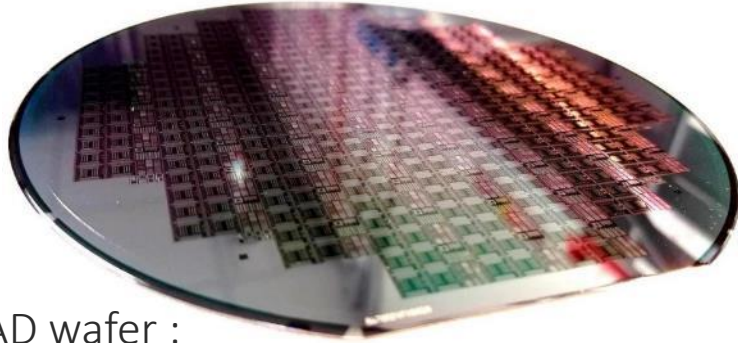


# 3D digital SiPM technology : SPAD array layer

- Top tier : 150 mm wafer (custom process using DALSA CCD production line)
- 1x1 to 5x5 mm<sup>2</sup> SPAD array
- 50-100  $\mu\text{m}$  diameter front-side illuminated shallow P+N type SPAD ( $\sim 0.4 \mu\text{m}$  depth)
- 4  $\mu\text{m}$  width / 22  $\mu\text{m}$  depth optical/electrical isolation trench (highly doped polysilicon filling)
- 2D process for SPAD development

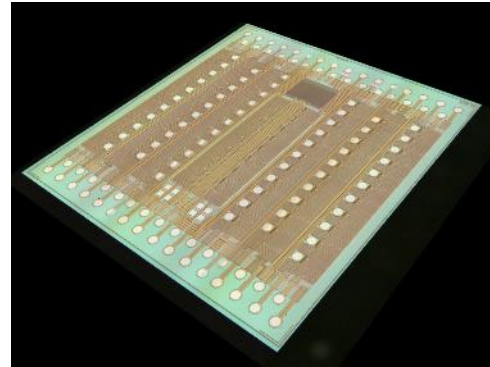
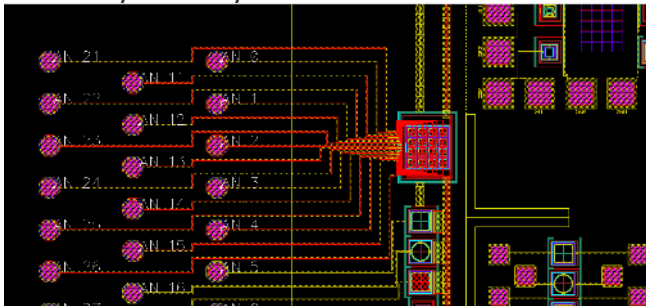


# SPAD development platform



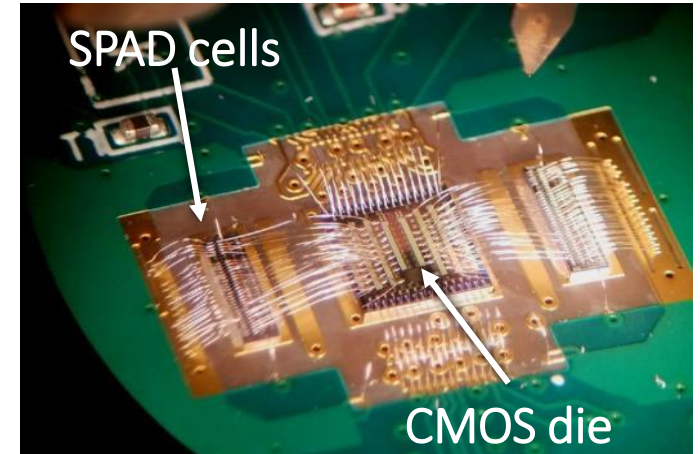
2D SPAD wafer :

- Single cell with variants
  - SPAD size and shape
  - process variation
- Small array (4 x 4 cells)
  - cell size and pitch
  - w/ or w/out trench

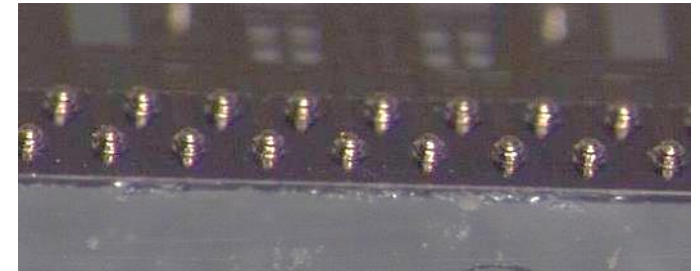


CMOS ASIC for SPAD probing

- TSMC CMOS 180 nm
- 64 quenching circuits
  - anode/cathode
  - up to 10 V excess voltage
  - variable input threshold
  - variable holdoff
- 4 outputs (MUX)



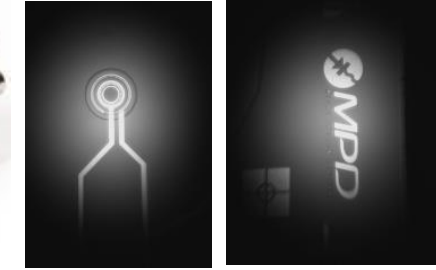
side-by-side wirebonding



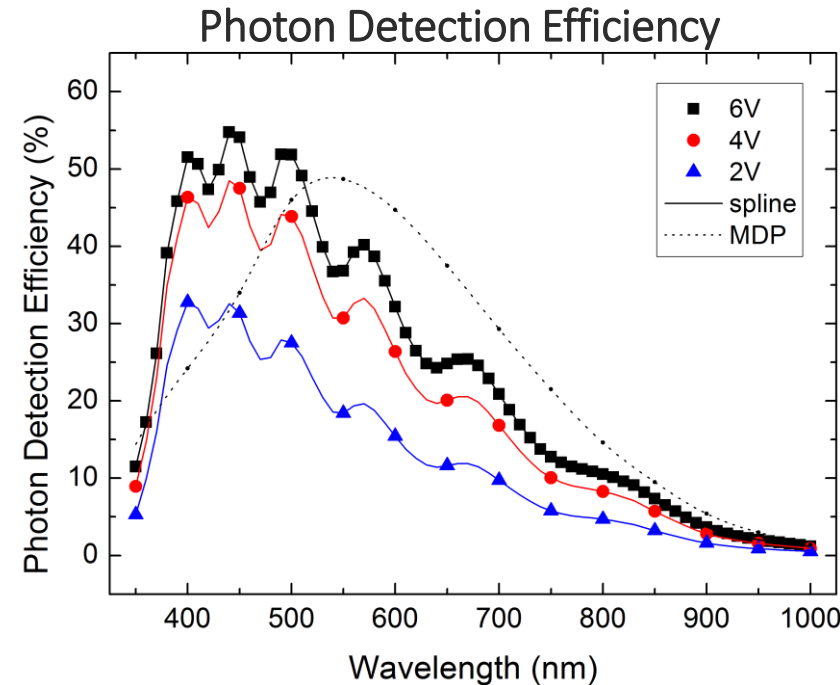
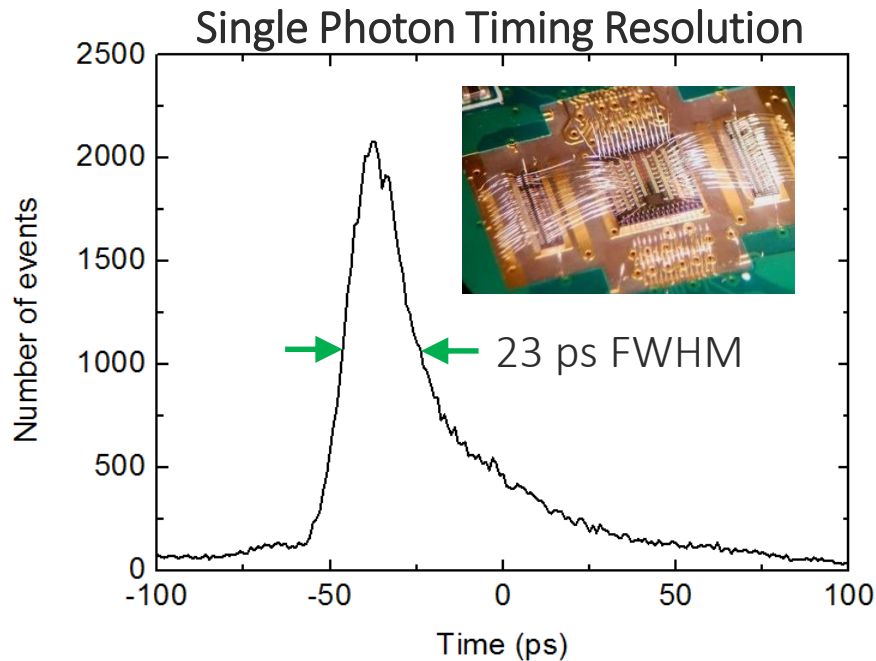
flipchip packaging

# 2D SPAD First Batch : Measurement Results

	2D SPAD	MPD PD5CT
Size (um)	36 um (square)	50 um (circle)
Breakdown / Overvoltage (V)	22.1 / 4	28.7 / 5
Dead time	100 ns - 10 us	300 ns
Single Photon Timing Resolution (ps FWHM)	23 @ 410 nm	27 @ 820 nm
Photon Detection Efficiency (%)	52% peak at 500 nm >30% at 390-600 nm	47% peak at 550 nm >30% at 450-700 nm



High-rate photon counting and picosecond timing with silicon-SPAD based compact detector modules A. Giudice (Journal of Modern Optics 2007)



400-500 nm range :

- fast scintillators for PET scanners

VUV range (< 200nm) :

- liquid Xe : 178 nm
- liquid Ar : 128 nm

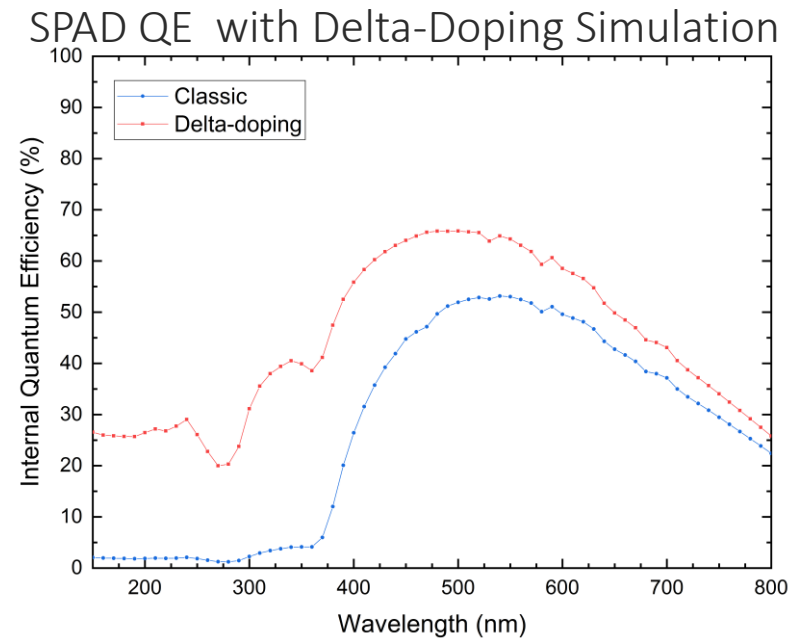
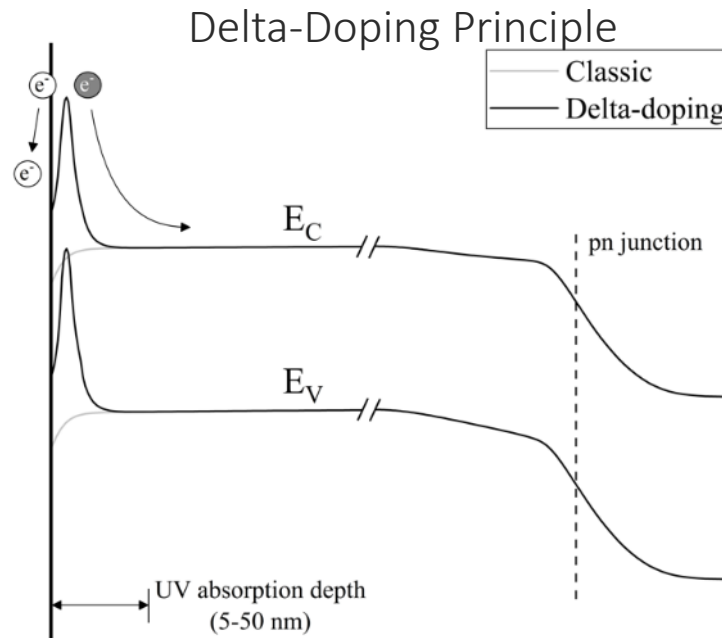
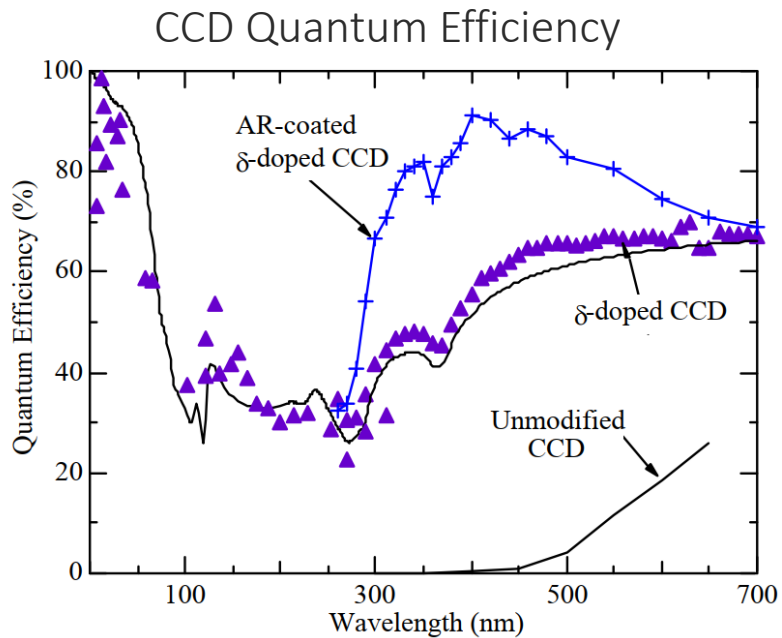
# VUV postprocessing for noble liquid experiments

- Delta-doping is used on CCDs to enhance the deep UV response
- Surface energy band engineering (ultra thin surface doping)
- UV-generated electrons drift towards the SPAD junction
- Simulation on SPAD demonstrates quantum efficiency improvement
- Will be use in addition to anti-reflective coating

Goals:

> 35% PDE at 175 nm (LXe)

> 15% PDE at 125 nm (LAr)



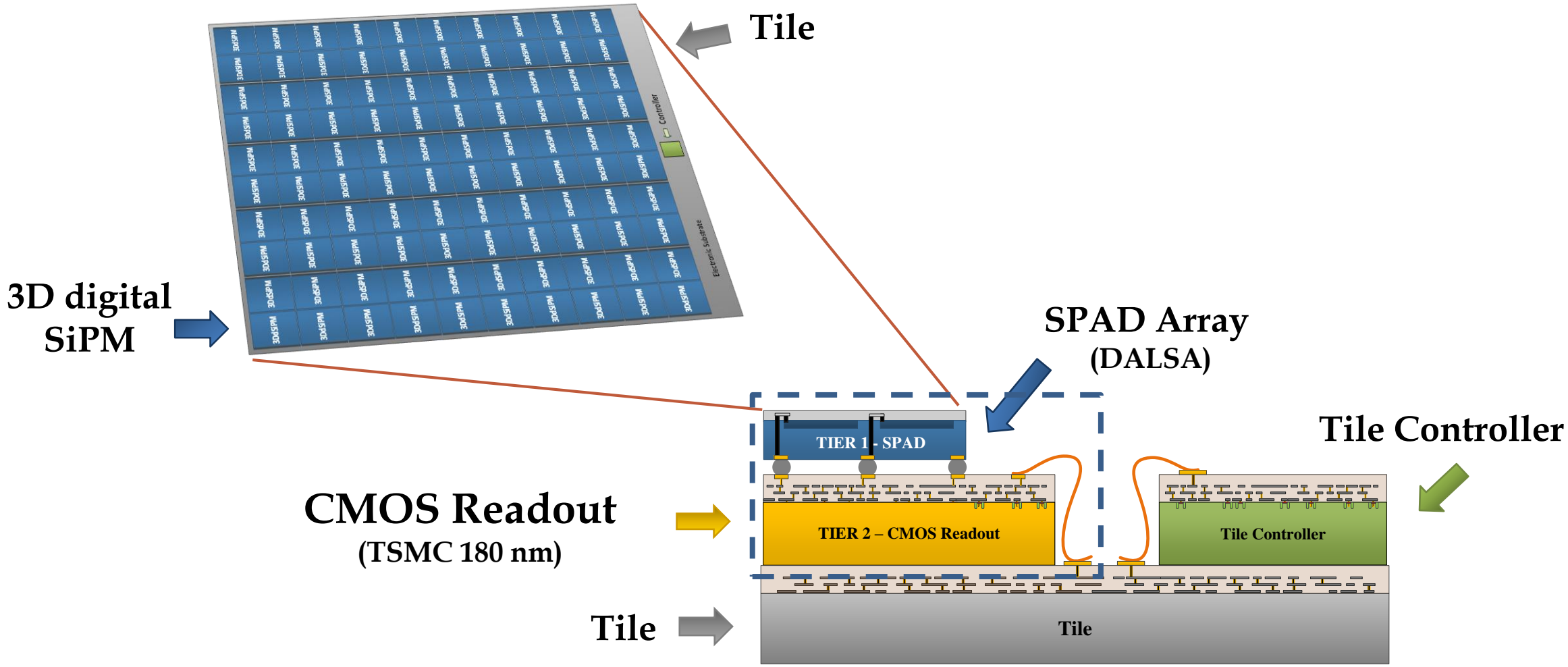
*Delta-doped back-illuminated CMOS imaging arrays: progress and prospects.*  
M.E. Hoenk (In Infrared Systems and Photoelectronic Technology IV 2009)

# Development of the 3DdSiPM Technology:

Microelectronic Readout Integrated Circuit for Low Power 3DdSiPM and Large Area Detectors



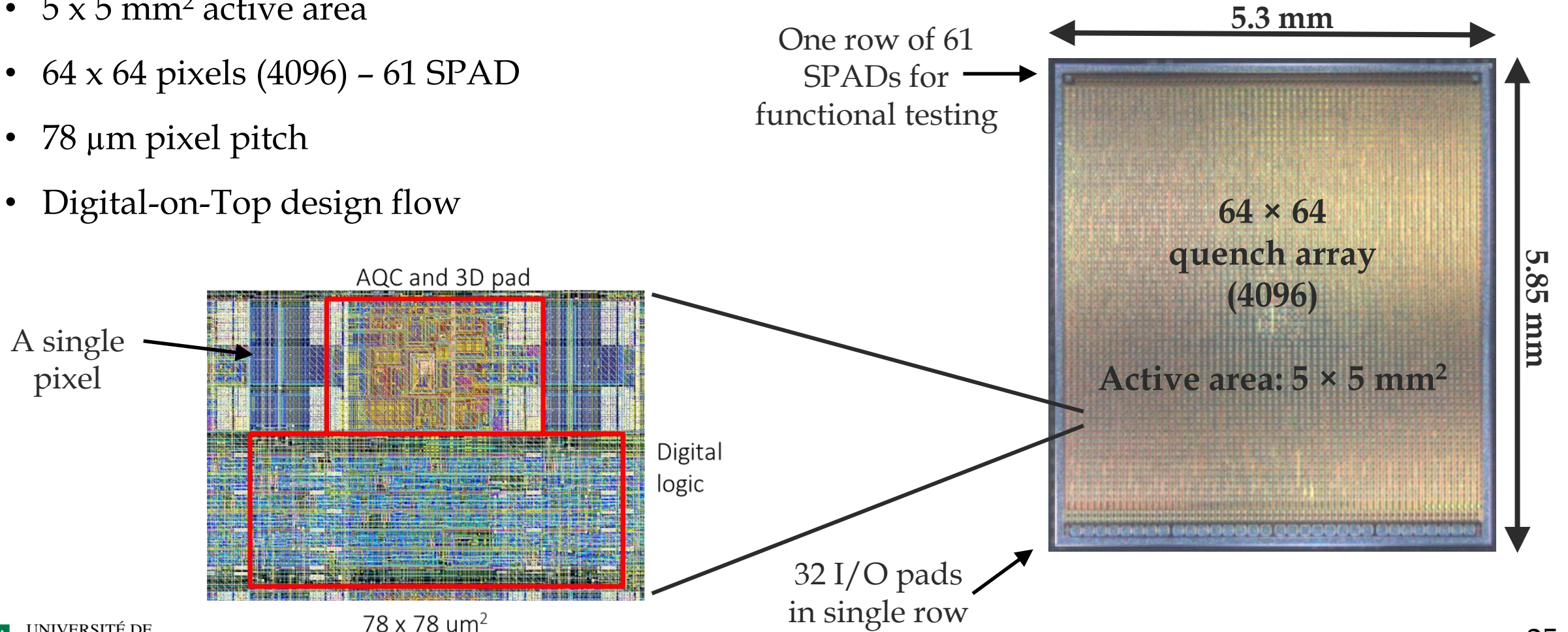
# 3DdSiPM on a Tile with a Controller





# CMOS Readout for 3DdSiPM – Overview

- TSMC 180 nm BCD process
- 5 x 5 mm<sup>2</sup> active area
- 64 x 64 pixels (4096) – 61 SPAD
- 78 μm pixel pitch
- Digital-on-Top design flow



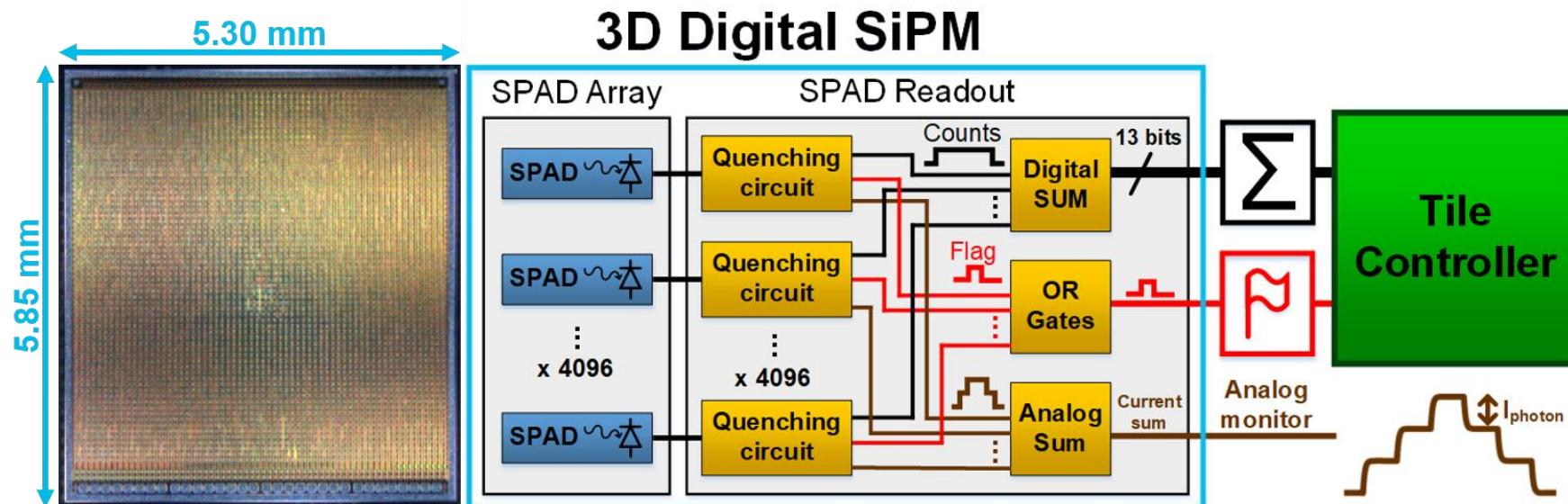
# CMOS Readout for 3DdSiPM – Low Power Architecture

- nEXO operation mode: **INTEGRATION**

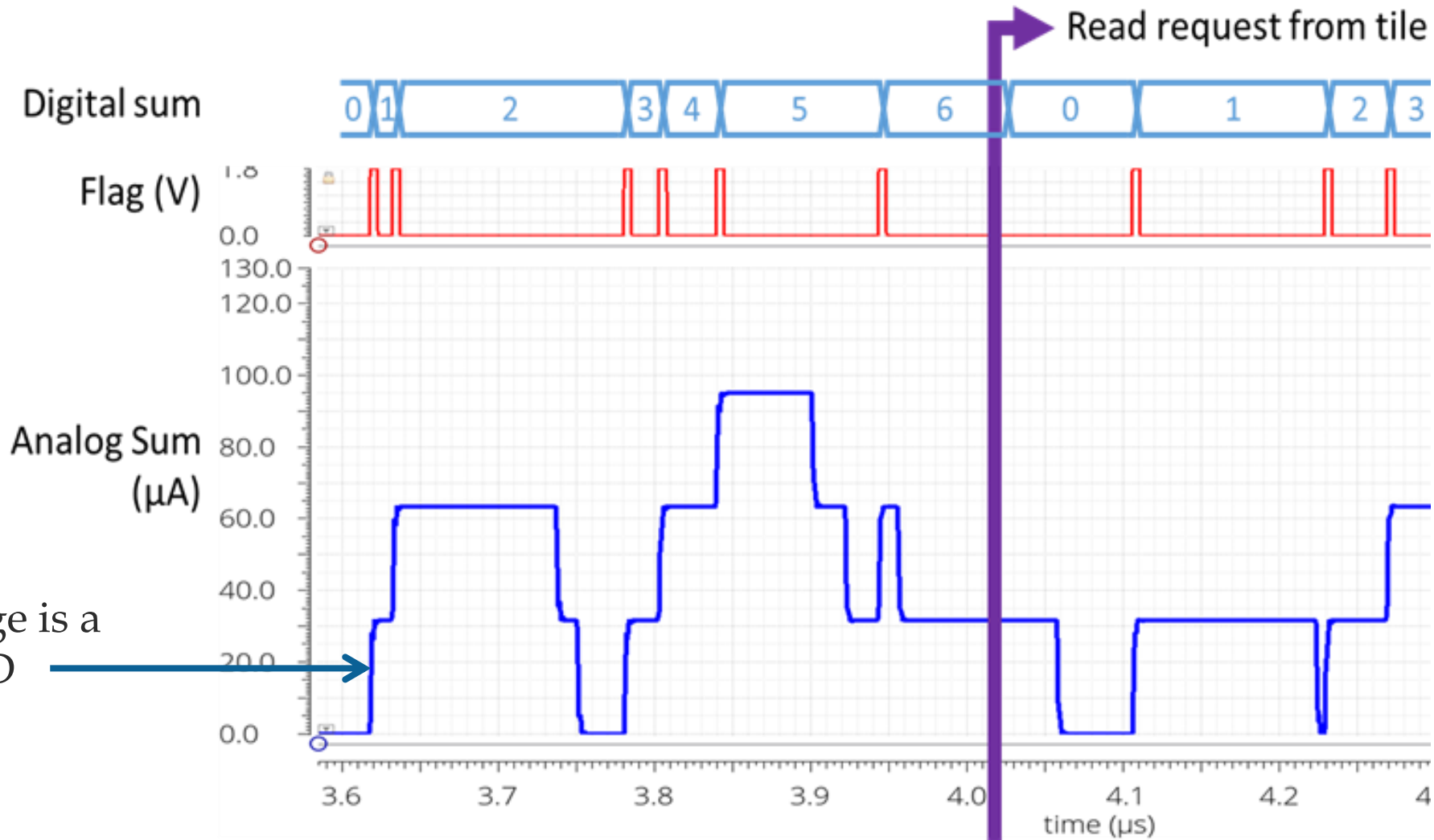
- Event driven: each 3DdSiPM signals the tile controller when a SPAD triggers
- **Asynchronous (no event no clock – low power)**
- Integration time from 10 ns to 1  $\mu$ s (350 ns)
- Transmission of total counts (over integration time) when requested by the tile controller
- Analog monitor for demonstration

- LAr operation mode: **CONTINUOUS SAMPLING**

- Synchronous operation by a clock
- Flags the controller to signal counts
- Low flag jitter (<500 ps) to allow time-of-flight
- 128 FIFO depth for transmission on request
- Sampling bins: short (10 ns) and long frames (1  $\mu$ s) to allow PSD (Pulse Shape Discrimination)



# Simulation of the 3 Outputs from the ASIC



Each rising edge is a triggered SPAD

# Coincidence / Dark Count Filter

- Single **flag** on a tile in a **coincidence window** : event rejected (dark count)

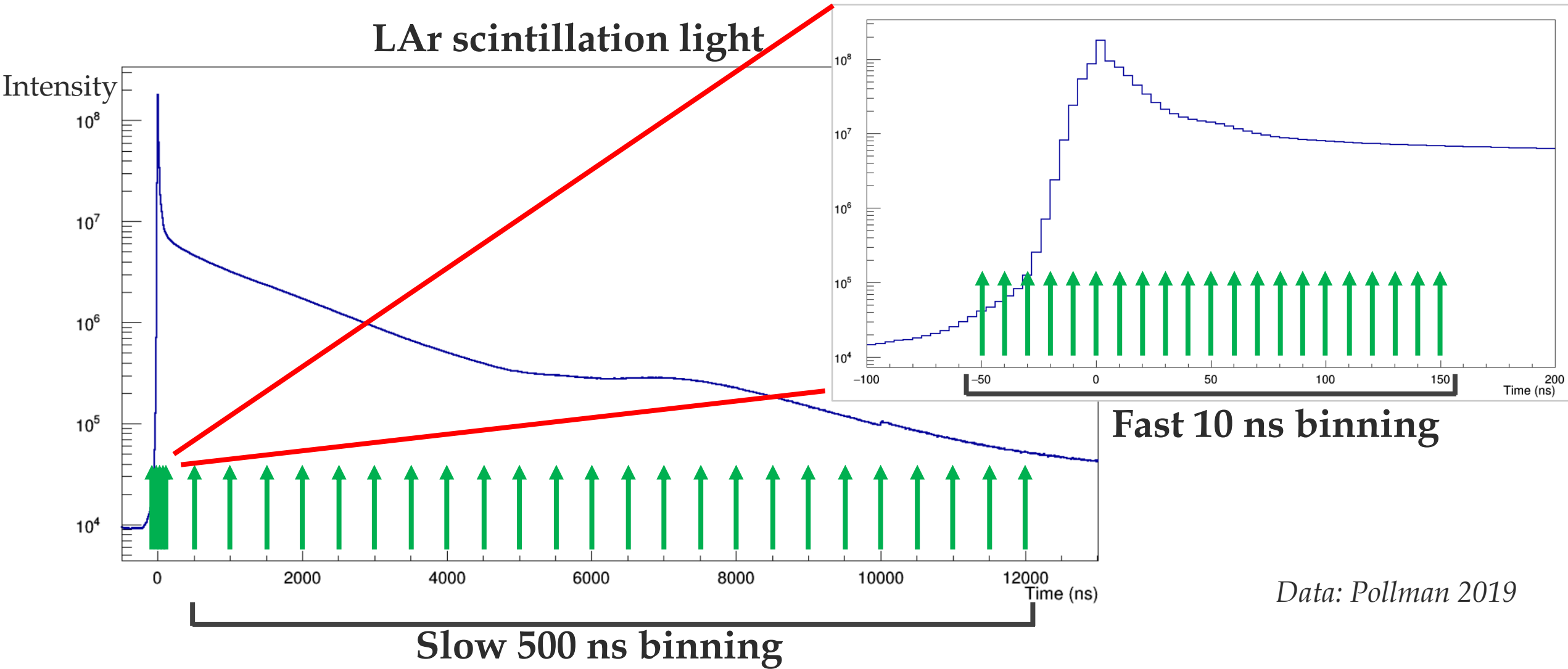


- Multiple **flags** on a tile in a **coincidence window** : start acquisition and read out after **acquisition time**



- **Coincidence window duration**, **acquisition time** and **flag threshold** managed by tile controller (programmable)
- Possibility to keep all **flags** (threshold of zero)
- No readout on dark count to limit power consumption

# Time Binning for Pulse Shape Discrimination in LAr



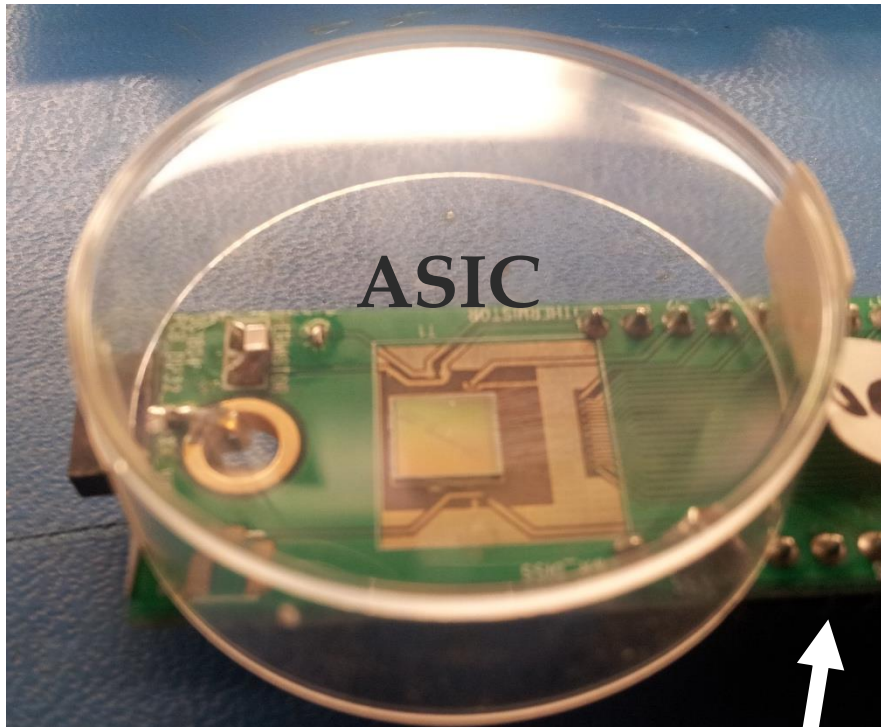
*Data: Pollman 2019*

# Microelectronic Readout Integrated Circuit for Low Power 3DdSiPM and Large Area Detectors

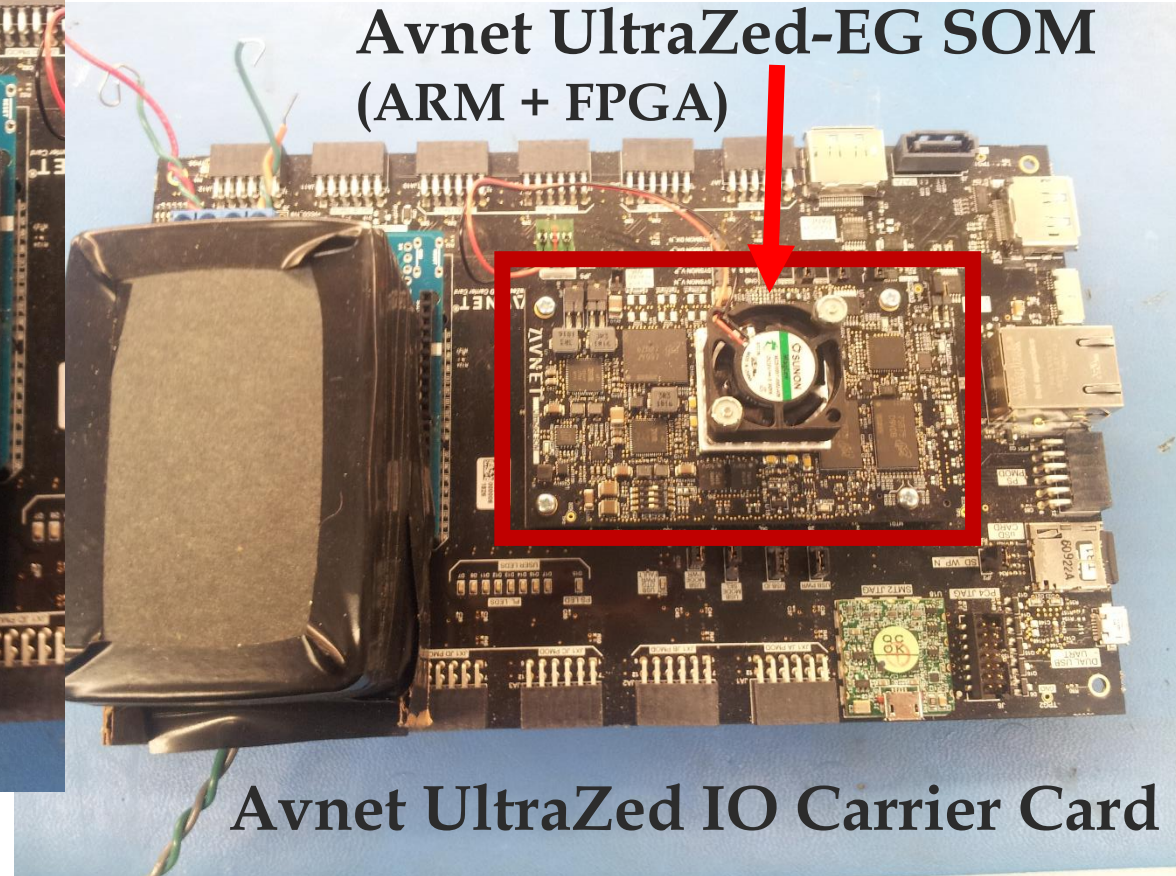
Measurements and Results



# « Apollo 13 » Setup – Functionnality Tests



**GENERIC ASIC TO DIP PCB**



**Avnet UltraZed-EG SOM  
(ARM + FPGA)**

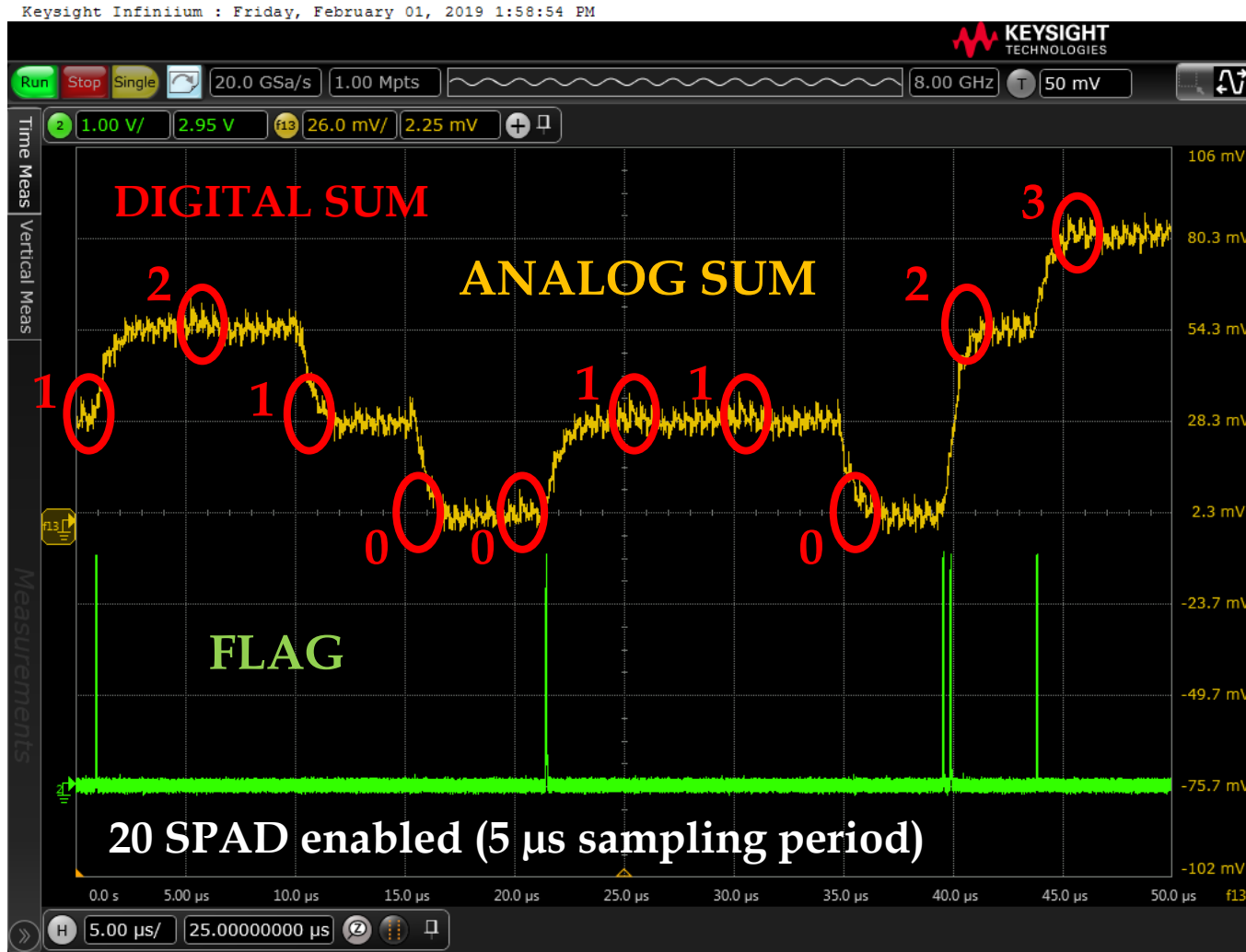
**Avnet UltraZed IO Carrier Card**

# « Apollo 13 » Setup – Functionnality Tests

- Poor PCB signal integrity : new PCB this week!
- 61 SPAD on the ASIC
- 90 % of the digital functionalities **tested** and **validated**
  - Flag, digital sum, FIFO, data transmission, ASIC configuration



# MEASURED - Integration Mode



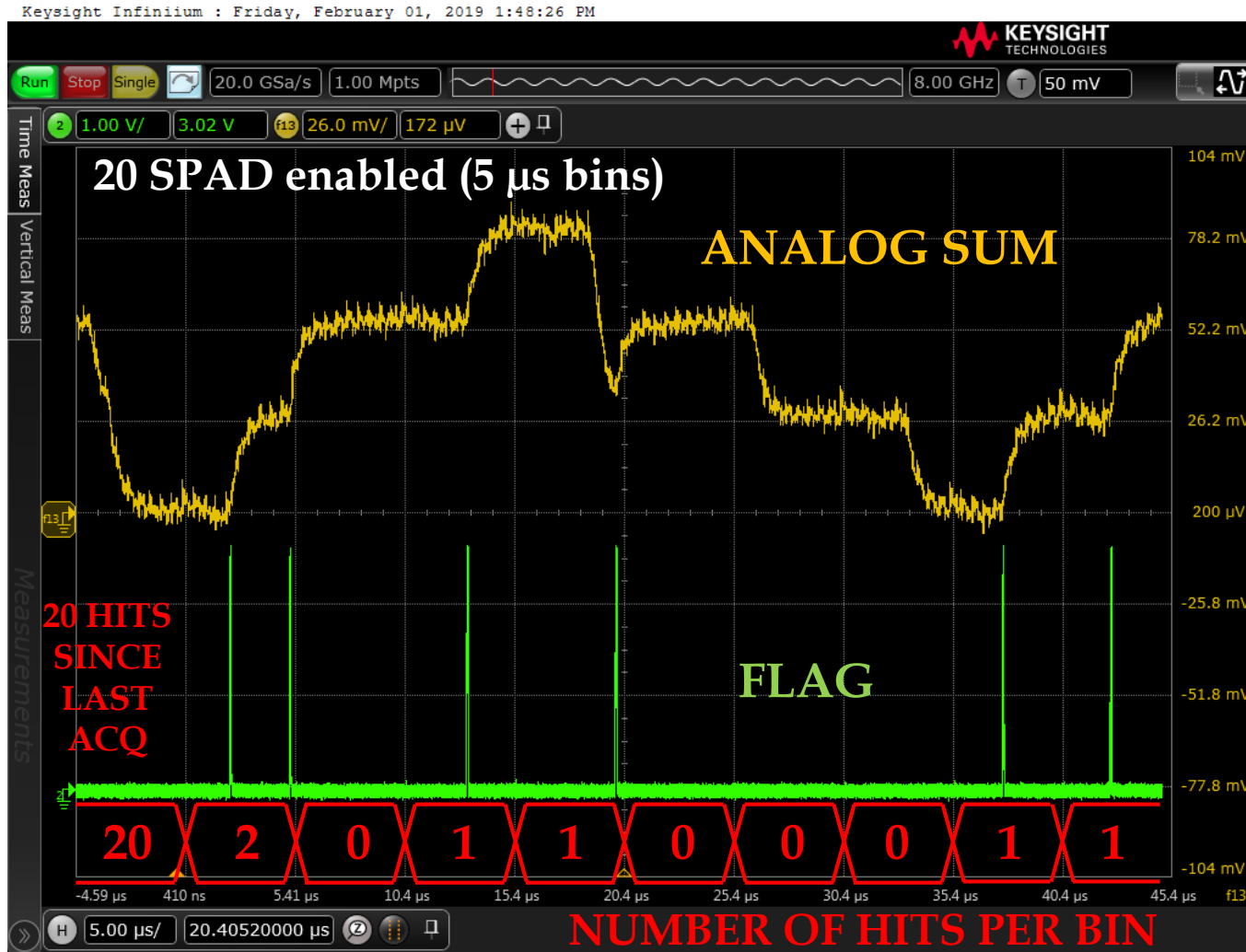
- ADC like acquisition
- Number of pixels triggered (in hold off) at the moment of the acquisition
- Each circle represents the result from the digital register

```

-----
READING 12 DATA      EMPTY FIFO
-----
./ASIC config 1v2.sh done
1 2 1 0 0 1 1 0 2 3 | 8191 8191
root@uz3eg-iocc-2018-2:~#
    
```

**DIGITAL SUM FROM ASIC**

# MEASURED – Binning Mode



- Time binning acquisition
- Number of pixels triggered in each time bin
- Each number represents the result from the digital register

```
-----  
READING 12 DATA      EMPTY FIFO  
-----  
./ASIC confia 1v2.sh done  
20 2 0 1 1 0 0 0 1 1 | 8191 8191  
root@uz3eg-iocc-2018-2:~#
```

DIGITAL SUM FROM ASIC

# Conclusion

- No fundamental limitation to build 3D digital SiPM, but it is a great engineering challenge.
- First 3D Digital SiPM expected in 2020.
- SPAD array, 3D integration and readout electronics developed and optimized in parallel.
  - Microelectronics readout soon ready for wafer level production.
  - SPAD R&D as fast as we can within Teledyne-DALSA.
  - Issue with 3D bonding: bad luck. Problem is now fixed.
- We are recruiting! Ph.D. and postdoc.
- In parallel with particle physics instrumentation, electronic readout for:
  - Positron Emission Tomography (PET) aiming at sub-10 ps FWHM coincidence timing resolution.
  - Photon gating Computed Tomography (CT) scanner.
  - Quantum key distribution.

# A team's work

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- Julien Sylvestre
- David Danovitch
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- Étienne Paradis
- Étienne Grondin
- Konin Koua
- Nicolas Roy
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- Samuel Parent
- Audrey Corbeil Therrien
- Benoit-Louis Bérubé
- Marc-André Tétrault
- Frédéric Vachon
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- Gabriel St-Hilaire
- Jacob Deschamps
- Xavier Bernard
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- Luc Maurais
- Maxime Côté
- Vincent Philippe Rhéaume
- Étienne Desaulniers Lamy
- Alexandre Boisvert
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- Arnaud Samson
- Jonathan Bouchard
- Frédéric Dubois
- Marc-Olivier Mercier
- Frédéric Bourque

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- Paul Lecoq
- nEXO Collaboration
- nEXO Canada
- Simon Viel

## Teledyne-DALSA Semiconducteur Inc

- Claude Jean (CEO)
- Stephane Martel
- Robert Groulx

